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Editors

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Introduction

The International Symposium on Precision Engineering Measurement and Instrumentation (ISPEMI) 2011 took place in Lijiang, China on 7–11 August 2011. Its approximately 230 attendees from 18 countries were treated to five days of talks, posters, technical exhibits, and special events, with ample opportunities for discussing measurement science and technology in precision engineering, making personal and scientific connections, and finding out the latest trends in our rapidly evolving interdisciplinary field. The ISPEMI program was organized into thirteen thematic sessions, and the chairs of each solicited manuscripts from their respective oral and poster presenters. These were compiled into the 7th ISPEMI proceedings volume.

The ISPEMI 2011 presentations were thematically diverse, as indicated by the session titles: Precision Theory and Uncertainty Evaluation, Micro/Nano Coordinate Measurement, Surface Measurement and Characterization, Optical Precision Measurement, etc. As you read this volume, you will encounter interesting studies for advanced dimensional, geometrical, micro structures, and material properties measurements using different methods, such as optical, tactile, electrical, NDT, etc. Such breadth and variety nicely illustrates the diversity of research in this exciting field. We hope that as you read this, you will be inspired to (and continue to) actively contribute to measurement and instrumentation research!

Kuang-Chao Fan
Rong-Sheng Lu
Man Song